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August 6, 2003

In Affiliation with
Weiss, Moy & Harris, PC
having offices in Arizona and Nevada,
and in Washington, DC with
Rabin & Berdo, PC

Mail Stop Patent Application

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Attorney Reference: MAE 292

Re: New Patent Application of: Jun KANAMORI
Title: SEMICONDUCTOR DEVICE FABRICATION METHOD USING
OXYGEN ION IMPLANTATION

Sir:

Please find attached hereto an application for patent which includes:

- [x] Specification, Claims and Abstract (14 Pages)
- [x] 4 Sheets of Formal Drawings (Fig. 1A through Fig. 5B)
- [x] Inventor's Declaration and Power of Attorney (3 Pages)
- [x] Assignment document with cover page (2 Pages)
- [x] Claim for priority and Priority document
- [x] Information Disclosure Statement, Form PTO-1449, and copies of 2 cited references
- [x] Form PTO-2038 (1 Page)
- [x] Fee (see formula below)

Basic Fee \$750/375 \$ 750.00

Additional Fees:

Total number of claims: 19
in excess of 20: 0 times \$18/9 \$ 0.00

Number of independent claims: 2
in excess of 3: 0 times \$84/42 \$ 0.00

Multiple Dependent Claims \$280/140 \$ 0.00

Recording Fee \$40. \$ 40.00

TOTAL FEES FOR THE ABOVE APPLICATION \$ 790.00

In the event there is attached hereto no credit card form PTO-2038 or check, or there is an insufficient amount, please charge the fee to our Account No. 18-0002 and notify us accordingly.

The rights of priority are claimed under 35 USC §119 of Japanese Application No. 2002-315882, filed October 30, 2002.

Respectfully submitted,

Robert H. Berdo, Jr. (Reg. No. 38,075)
Customer No. 23995

August 6, 2003

Date

RHB:tz

